

IN THE ABSTRACT:

Please delete prior Abstract and insert the following Abstract starting at page 42, line 2 and ending at line 8.

--A sample processing apparatus includes a probe, a probe mover for moving the probe such that the probe is brought into contact with a part of a sample, an adhering device for adhering the probe to the part of the sample, and an ion beam generator for irradiating the sample with an ion beam to separate the part of the sample from a remaining body of the sample. A temperature controller controls temperatures of the probe and the sample individually to prevent a temperature change of the part of the sample when the probe is brought into contact with the part of the sample and when the sample is irradiated with an ion beam by the ion beam generator.--